

1753

Applicant: Chung-En Kao

Group Art Unit: 1753

Serial No.: 09/976,082

Examiner: Steven H. Versteeg

Filed: Oct. 12, 2001

In Response to Office Action  
Dated: November 8, 2002

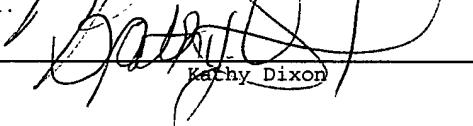
For: Apparatus And Method For Self-Centering A Wafer  
In A Sputter Chamber

Attorney Docket No.: 67,200-530

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TC 1700

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

  
Kathy Dixon

Date: Feb 12, 2003

RESPONSE TO OFFICE ACTION

Assistant Commissioner  
for Patents  
Washington, D.C. 20231

Dear Sir:

In response to an Office Action mailed Nov. 8, 2002,  
please enter the following amendments and consider the following  
remarks. Applicants hereby respectfully request and petition for

03/24/2003 WHITED DRAFTED extension of time up to and including March 8, 2003 to  
01 FC:1251 110.00 CH respond to the Official Action dated November 8, 2002